L Number	Hits	Search Text	DB	Time stamp
-	2	("6122042").PN.	USPAT; US-PGPUB;	2004/02/29 15:47
-	2	("20020003169").PN.	EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/02/29 19:03
-	2	("6222208").PN.	DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/02/29 15:58
_	489	(257/254,471).CCLS.	DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/02/29
_	19	display and ((257/254,471).CCLS.)	DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO;	2004/02/29 17:22
_	107919	(micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors)	DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;	2004/02/29 16:47
_	1117	(pixels or pixel) and ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors))	IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;	2004/02/29 16:47
_	3018	<pre>pitch and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors))</pre>	IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;	2004/02/29 16:49
-	20505	((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors))	IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT;	2004/02/29 16:48
	1371	pitch and (((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) near1 (sensor or sensors)))	IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/02/29 16:49
_	380	substrate and (pitch and (((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or	USPAT; US-PGPUB; EPO; JPO; DERWENT;	2004/02/29 16:55
_	0	sensors)))) (substrate near2 semicodncutor) and (pitch and (((light adj1 emitting) or led or display) and ((micromechanical or	IBM_TDB USPAT;	2004/02/29 16:56
	70	strain or pressure or piezoelectric) nearl (sensor or sensors)))) (substrate near2 semiconductor) and (pitch and (((light adj1 emitting) or led or display) and ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors))))	DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/02/29 17:16

1163 (integrade or integrated or intergarting) USFAT;					
	_	1163		USPAT;	i i
DEWENT: IBM TDB USPAT:			with display with sensor	1	17:17
Integrated or integrated or intergrating USPAT;				, ,	
- 30	j j			· ·	
				_	0004/00/00
2004/02/29 200	-	30		·	
DERMENT;			with display with sensor with logic	·	17:21
-					i
467490 ((wafer or substrate) with semiconductor) USPAT; 2004/02/29 17:21 17:21 18:25 17:21 18:25 17:21 18:25 1				· ·	
1483 display same ("pn" or "p-n") Same ("imiromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors) USPAT: USPA				—	
1483 display same ("pn" or "p-n") Same (spo; po; po; po; po; po; po; po; po; po;	-	467490	((wafer or substrate) with semiconductor)		
1483 display same ("pn" or "p-n") DERWENT; ISM TDB US-PGPUB; EPO; JPO; DERWENT;				· ·	17:21
1483 display same ("pn" or "p-n") Same (Spany same ("pn" or "p-n") Same (Imicromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors) 17:25 17:2				· · · · · · · · · · · · · · · · · · ·	
1483 display same ("pn" or "p-n")				i i	
4				<u> </u>	0004/00/00
Continue	-	1483	display same ("pn" or "p-n")	1	1
-				1	17:25
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((micromechanical or strain or pressure or piezoelectric) nearl (sensor or EPO, JPO; sensors))			, , , , , , , , , , , , , , , , , , ,	<u> </u>	0004/00/00
Or piezoelectric) nearl (sensor or sensors)	-	4			1
Sensors DERMENT; IBM TDB USPAT; US-PGPUB; EPO; JPO; DERMENT; IBM TDB USPAT; US-PGPUB; EPO; JPO; DERMENT; IBM TDB USPAT; US-PGPUB; USPAT; US-PGPUB; USPAT; US-PGPUB; USPAT; US-PGPUB; USPAT;			•	i i	17:25
Soles display same (pixel or pixels)			-	· · · · · · · · · · · · · · · · · · ·	
Sole			sensors))	, '	
Comparison of the comparison					2004/02/20
- 21 (display same (pixel or pixels)) same (micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors) US-PGPUB; EPO, JPO; DERWENT; IBM TDB USPAT; US-PGPUB; IBM TDB USPA	-	80185	display same (pixel or pixels)		
-				· ·	1/:40
- 21 (display same (pixel or pixels)) same ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors)) - 12310 display same (pitch) - 24 (display same (pitch)) same ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or perwent; IBM_TDB US-PAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB US-PAT; US-PGPUB; EPO; JPO; US-PGPUB; US-PGPUB; US-PGPUB; US-PGPUB;			; 		
Cold				1	
((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors)) 12310 display same (pitch) 24 (display same (pitch)) same (micromechanical or strain or pressure or piezoelectric) nearl (sensor or persoure or piezoelectric) nearl (sensor or sensors)) 25 (micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors)) 26 (strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) 27 (gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or gas or rf or electrical) with (sensor or gauge)) 28 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (substrate or wafer) with (semiconductor or semiconductive) 2004/02/29 2004/02/29 17:41 2004/02/29 17:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51		0.1	(1'	_	2004/02/20
or piezoelectric) nearl (sensor or sensors) 12310 display same (pitch) 13210 display	_	21	, ,		
Sensors DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; USPAUB; EPO; JPO; USPAT;					1/:41
display same (pitch) TBM_TDB	1			1	
12310 display same (pitch) USPĀT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB USPĀT; US-PGPUB; EPO; JPO; DERWENT; IBM TDB USPĀT; US-PGPUB; US-PGPUB; US-PGPUB; US-PGPUB; US-PGPUB; EPO; JPO; DERWENT; IBM TDB USPĀT; US-PGPUB; US-PGPUB; US-PGPUB; EPO; JPO; DERWENT; IBM TDB USPĀT; US-PGPUB; US-PGPUB; EPO; JPO; US-PGPUB;			sensors))	1	
Comparison of the comparison		10010	di and an anno (mitob)	· —	2004/02/20
- 24 (display same (pitch)) same ((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors)) - 443238 (strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) - 7978 ((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or emitting))) - 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or sf or electrical) with (sensor or emitting)) - 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (EPC); JPO; DERWENT; IBM TDB (USPAT; US-PGPUB; EPC); JPO; US-PGPUB; EPC); JPO; JPO; DERWENT; IBM TDB (USPAT; US-PGPUB; EPC); JPO; JPO; US-PGPUB; EPC); JPO; JPO; JPO; JPO; JPO; JPO; JPO; JPO	_	12310	display same (pitch)	1	· ·
Comparison of the properties					1/:41
- 24 (display same (pitch)) same (mitch)) same (m				,	
- 24 (display same (pitch)) same (micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors)) - 443238 (strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) - 7978 ((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) - 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (emitter or emitting))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) USPĀT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPĀT; US-PGPUB; EPO; JPO; US					
((micromechanical or strain or pressure or piezoelectric) nearl (sensor or sensors)) 443238 (strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) 7978 ((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or gas or rf or electrical) with (sensor or gauge)) ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (emitter or gauge)) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (emitter or emitting))) 469803 (strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (emitter or emitting))) (substrate or wafer) with (semiconductor or semiconductive) USPAT; USPAT; USPAT; USPAT; USPAT; USPGPUB; EPO; JPO; USPGPUB; EPO; JPO;		24	/diamlass games /mitch\ \ came		2004/02/29
or piezoelectric) nearl (sensor or sensors)) - 443238 (strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) - 7978 ((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or emitting))) - 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (emitter or emitting))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) USPAT; US-PGPUB; EPO; JPO; USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	-	24			
Sensors)) - 443238 (strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) - 7978 ((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or emitting))) - 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) DERWENT; IBM_TDB US-PGPUB; EPO; JPO; DERWENT; IBM_TDB 2004/02/29 US-PGPUB; EPO; JPO; US-PGPUB; IB:51 US-PGPUB; IBM_TDB 2004/02/29 US-PGPUB; IBM_TDB 2004/02/29 US-PGPUB; IBM_TDB			1 ' '	·	17.01
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accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge) 7978 ((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or gas or rf or electrical) with (sensor or gas or rf or electrical) with (sensor or gas or rf or electrical) with (sensor or gauge) and ((gallium adjl arsenide) or gas or rf or electrical) with (sensor or gauge) and ((gallium adjl arsenide) or gas) same (display or led or (light adjl (emitter or emitting))) 469803 (substrate or wafer) with (semiconductor or semiconductive) 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 18:51 2004/02/29 17:56	_	443339	(strain or pressure or temperature or		2004/02/29
or gas or rf or electrical) with (sensor or gauge) 7978 ((gallium adj1 arsenide) or gaas) same (display or led or (light adj1 (emitter or emitting))) ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adj1 arsenide) or gas) same (display or led or (light adj1 (emitter or emitting))) 469803 (substrate or wafer) with (semiconductor or semiconductive) PO; JPO; DERWENT; IBM_TDB USPĀT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPĀT; US-PGPUB; EPO; JPO; USPAT; US-PGPUB; EPO; JPO; US-PGPUB; EPO; JPO; US-PGPUB; EPO; JPO; US-PGPUB; EPO; JPO;		173230	'	1	1
or gauge) - 7978 ((gallium adj1 arsenide) or gaas) same (display or led or (light adj1 (emitter or emitting))) - 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adj1 arsenide) or gas) same (display or led or (light adj1 (emitter or emitting))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; US-PGPUB; EPO; JPO; USPAT; US-PGPUB; EPO; JPO; USPAT; US-PGPUB; EPO; JPO;	!		· · · · · · · · · · · · · · · · · · ·		
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- 7978 ((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or emitting))) - 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) 469803 (gallium adjl (emitter or gaas) same (display or led or (light adjl (emitter or emitting)))) (substrate or wafer) with (semiconductor or semiconductive) 469803 (18:49 (USPAT; USPAT; USP]	,	1	
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or emitting))) - 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gas) same (display or led or (light adjl (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) EPO; JPO; DERWENT; EPO; JPO; DERWENT; IBM_TDB USPAT; USPAT; USPAT; USPAT; USPAT; USPAT; USPAT; USPAT; OR SEMENT; SE		,,,,	- · · · · · · · · · · · · · · · · · · ·		
- 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) DERWENT; US-PGPUB; EPO; JPO; USPAT; U					
- 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adj1 arsenide) or gas) same (display or led or (light adj1 (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) JBM_TDB 2004/02/29 18:51		ļ			
- 384 ((strain or pressure or temperature or accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adj1 arsenide) or gaas) same (display or led or (light adj1 (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) 469803 (substrate or wafer) with (semiconductor or semiconductive) USPAT; IBM_TDB USPAT; USPA				1	
accelerometer or inertial or ph or sound or gas or rf or electrical) with (sensor or gauge)) and (((gallium adjl arsenide) or gaas) same (display or led or (light adjl (emitter or emitting)))) 469803 (substrate or wafer) with (semiconductor or semiconductive) US-PGPUB; EPO; JPO; DERWENT; IBM_TDB USPAT; USPAT; US-PGPUB; T7:56	_	384	((strain or pressure or temperature or		2004/02/29
or gas or rf or electrical) with (sensor or gauge)) and (((gallium adj1 arsenide) or gaas) same (display or led or (light adj1 (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) USPAT; USPAT; US-PGPUB; EPO; JPO;			• • • • • • • • • • • • • • • • • • • •	i i	•
or gauge)) and (((gallium adj1 arsenide) DERWENT; or gaas) same (display or led or (light adj1 (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor or semiconductive) Or gauge)) and (((gallium adj1 arsenide) DERWENT; IBM_TDB USPAT; 2004/02/29 USPAT; US-PGPUB; 17:56 EPO; JPO;		1	-		
or gaas) same (display or led or (light adjl (emitter or emitting))) - 469803 (substrate or wafer) with (semiconductor USPAT; 2004/02/29 or semiconductive) USPAT; 2004/02/29 US-PGPUB; 17:56 EPO; JPO;					
adjl (emitter or emitting)))) - 469803 (substrate or wafer) with (semiconductor USPAT; 2004/02/29 or semiconductive) US-PGPUB; EPO; JPO;					
- 469803 (substrate or wafer) with (semiconductor USPAT; 2004/02/29 or semiconductive) US-PGPUB; 17:56 EPO; JPO;		<u> </u>		-	
or semiconductive) US-PGPUB; 17:56 EPO; JPO;	-	469803		USPAT;	2004/02/29
EPO; JPO;			†		
DERWENT:				EPO; JPO;	
				DERWENT;	
IBM_TDB				IBM_TDB	

_	104	(((strain or pressure or temperature or	USPAT;	2004/02/29
		accelerometer or inertial or ph or sound	US-PGPUB;	18:50
		or gas or rf or electrical) with (sensor	EPO; JPO;	
		or gauge)) and (((gallium adjl arsenide)	DERWENT;	• '
		or gaas) same (display or led or (light	IBM_TDB	
		adj1 (emitter or emitting))))) and		
		((substrate or wafer) with (semiconductor		
		or semiconductive))		
-	61675	display and ((strain or pressure or	USPAT;	2004/02/29
		temperature or accelerometer or inertial	US-PGPUB;	18:51
		or ph or sound or gas or rf or	EPO; JPO;	
		electrical) with (sensor or gauge)).	DERWENT;	
	12066		IBM_TDB	2004/02/20
-	13966	' ' · · · · · · · · · · · · · · · · ·	USPAT;	2004/02/29
		accelerometer or inertial or ph or sound	US-PGPUB;	18:51
	1	or gas or rf or electrical) with (sensor	EPO; JPO;	
		or gauge)) and (((wafer or substrate)	DERWENT;	
	0574	with semiconductor))	IBM_TDB	2004/02/20
_	2574	display and (((strain or pressure or	USPAT;	2004/02/29
		temperature or accelerometer or inertial	US-PGPUB;	18:51
		or ph or sound or gas or rf or	EPO; JPO;	
		electrical) with (sensor or gauge)) and	DERWENT;	
		(((wafer or substrate) with	IBM_TDB	
_	20961	semiconductor))) ((strain or pressure or temperature or	USPAT;	2004/02/29
_	20901	accelerometer or inertial or ph or sound	US-PGPUB;	18:51
		or gas or rf or electrical) with (sensor	EPO; JPO;	10.51
		or gauge)) same display	DERWENT;	
		or gauge // same drspray	IBM TDB	
_	487	(((strain or pressure or temperature or	USPAT;	2004/03/01
	10,	accelerometer or inertial or ph or sound	US-PGPUB;	14:00
		or gas or rf or electrical) with (sensor	EPO; JPO;	
		or gauge)) same display) and (((wafer or	DERWENT;	
		substrate) with semiconductor))	IBM TDB	
_	2	("5324980").PN.	USPAT;	2004/03/01
	_	(US-PGPUB;	15:57
	}		EPO; JPO;	
			DERWENT;	
			IBM TDB	
_	15	5324980.URPN.	USPAT	2004/03/01
				14:00
-	0	("strainwithpressurewithsensor").PN.	USPAT;	2004/03/01
			US-PGPUB;	15:58
			EPO; JPO;	
			DERWENT;	
			IBM_TDB	
_	3304	strain with pressure with sensor	USPAT;	2004/03/01
			US-PGPUB;	15:58
			EPO; JPO;	·· ·
			DERWENT;	
			IBM_TDB	2004/02/03
-	149	· ·	USPAT;	2004/03/01
		semiconductor adj substrate	US-PGPUB;	16:14
			EPO; JPO;	
			DERWENT;	
	_		IBM_TDB	2004/02/01
-	6	display same pitch same gaas	USPAT;	2004/03/01
			US-PGPUB;	16:14
			EPO; JPO;]
			DERWENT;	
	<u> </u>	<u> </u>	IBM_TDB	<u> </u>